

FORM PTO-1449		U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE		ATTORNEY DOCKET NO. 2077.D1/SILICON/MBE						09/597,778 SERIAL NO.: NA			
LIST OF ART CITED BY APPLICANT (Use several sheets if necessary)		APPLICANT: Grimbergen, et al.						FILING DATE: Herewith			GROUP: 1746 <u>Unknown</u>		
		U.S. PATENT DOCUMENTS											
Examiner Initial		DOCKET NUMBER						DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE	
Alvarez	A1*	4	1	9	8	2	6	1	4/15/80	Busta, et al.	156	626	09/595,220
	A2*	4	2	0	8	2	4	0	6/17/80	Latos	156	627	09/595,220
	A3*	4	4	9	3	7	4	5	1/15/85	Chen, et al.	156	628	09/595,220
	A4*	4	8	4	2	6	8	3	6/27/89	Cheng, et al.	156	345	09/595,220
	A5*	4	8	5	9	2	7	7	8/22/89	Barna, et al.	156	624	09/595,220
	A6*	4	9	5	3	9	8	2	09/1998	Ebbing, et al.	356	357	09/595,220
	A7*	4	9	7	5	1	4	1	12/04/90	Greco, et al.	156	626	09/595,220
	A8*	5	0	0	2	6	3	1	03/26/91	Giapis, et al.	156	643	09/595,220
	A9*	5	2	0	0	0	2	3	4/6/93	Gifford, et al.	156	626	09/595,220
	A10*	5	3	6	2	3	5	6	11/8/94	Schoenborn	156	626	09/595,220
	A11*	5	3	7	2	6	7	3	12/1994	Stager, et al	438	008	09/595,220
	A12*	5	3	7	2	6	7	3	12/1994	Stager, et al			DUPLICATE
	A13*	5	3	9	2	1	2	4	2/21/95	Barbee, et al	356	381	09/595,220
	A14*	5	3	9	9	2	2	9	3/21/95	Stefani, et al	156	626	09/595,220
	A15*	5	4	0	3	4	3	3	4/1995	Morrison, et al.	216	060	09/595,220
	A16*	5	4	0	6	0	8	0	4/11/95	Friedheim	250	309	09/595,220
	A17*	5	4	4	5	7	0	5	8/29/95	Barbee, et al.	156	627.1	09/595,220
	A18*	5	4	5	0	2	0	5	9/12/95	Sawin, et al	356	382	09/595,220
	A19*	5	4	5	1	2	8	9	9/19/95	Barbee, et al.	216	059	09/595,220
	A20*	5	4	5	6	7	8	8	10/10/95	Barbee, et al.	156	345	09/595,220
	A21*	5	4	6	7	8	8	3	11/21/95	Frye, et al.	216	060	09/595,220
	A22*	5	4	7	2	5	0	8	12/1995	Saxena	118	723EE	09/595,220
	A23*	5	5	3	6	3	5	9	7/1996	Kawada, et al.	438	016	09/595,220
	A24	5	6	5	4	9	0	3	8/5/97	Reitman, et al.	364	551.01	09/595,220
	A25	5	6	9	1	5	4	0	11/25/97	Halle, et al.	250	372	09/595,220
	A26*	5	7	1	6	4	5	1	2/10/98	Hama, et al.	118	723	09/595,220
	A27	5	7	4	7	3	8	0	5/5/98	Yu, et al	438	599	09/595,220
	A28*	5	7	7	0	0	9	7	6/1998	O'Neill, et al.	216	060	09/595,220
	A29*	5	7	9	2	2	7	2	8/1998	Van Os, et al.	118	723R	09/595,220
Alvarez	A30*	5	8	0	7	7	6	1	09/1998	Coronel, et al.	438	014	09/595,220
EXAMINER <i>Alvarez</i>										DATE CONSIDERED <i>4/16/02</i>			
EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.													

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		APPLICANT: Grimbergen, et al.								FILING DATE: Herewith		GROUP: 1746 Unknown	
		U.S. PATENT DOCUMENTS											
Examiner Initial		DOCKET NUMBER							DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE
<i>Ma</i>	A31	5	8	3	4	3	7	5	11/10/98	Chen	438	692	<i>09/595,778</i> C829 U.S. PRC
<i>Ma</i>	A32*	5	8	4	6	8	8	3	12/8/98	Moslehi	438	711	<i>09/595,778</i> 06/16/00
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EXAMINER <i>Ma. Oba</i>										DATE CONSIDERED <i>4/16/02</i>			
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		APPLICANT: Grimbergen, ET AL.								FILING DATE: Herwith		GROUP: 1746		
		FOREIGN PATENT DOCUMENTS												
		DOCKET NUMBER							DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION	
		YES	NO											
<i>Arc</i>	B1*	0	7	3	5	5	6	5	02/10/96	EP APPLICATION	—	—		
<i>Arc</i>	B2	0	7	5	6	3	1	8	1/19/97	EP APPLICATION	HOIL	21/66	00	00
<i>Arc</i>	B3*	0	7	8	8	1	3	8	08/06/97	EP APPLICATION	—	—	00	00
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EXAMINER	<i>Allan W. Ober</i>										DATE CONSIDERED <i>7/16/02</i>			
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FORM PTO-1449		U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE	ATTORNEY DOCKET NO. 2007.D1/USA/SILICON/MBE	09/395-778 SERIAL NO. <i>NA</i>
LIST OF ART CITED BY APPLICANT (Use several sheets if necessary)		APPLICANT: Grimbergen, et al.		
		FILING DATE: Herewith	GROUP: <i>Unknown</i>	
OTHER ART (Including Author, Title, Date, Pertinent Pages, etc.)				
<i>Acu</i>	C1*	International Search Report, dated February 17, 1999		
	C2*	Principles of Instrumental Analysis, 2 nd Ed., Skoog and West (Saunders, 1980) pages 181, 182, 193, 245		
	C3*	Sofie Instruments- Product User's Manual, Digitwin		
	C4*	""In-Situ Control and Diagnosis of Deposition and Etch Processes is Possible Using Interferometry Combined with CCD Imaging", European Semiconductor, March 1995, pages 14-17		
<i>Acu</i>	C5*	F. Heinrich; P. Kopperschmidt, "Online Uniformity Measurements in Large Area Plasma Assisted Etching and Deposition", Proceedings of the 10 th International Colloquim on Plasma Processes CIP '95", Antibes, France, June 11-15 1995		
	C6			
	C7			
	C8			
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	C18			
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	C20			
EXAMINER <i>Mac. Oba</i>		DATE CONSIDERED <i>4/16/02</i>		
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